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Ferroelectricity News

A quarterly update on what's happening in the field of ferroelectric

Volume 7, Number 2

WORLDWIDE FERROELECTRICITY RESEARCH:	
INTERDISCIPLINARY IN NATURE	IN THI
Leafing through conference announcements, meeting reports, or symposium	From the
proceedings, one cannot help but be struck by the interlacing and overlapping quality of research in the field of ferroelectricity.	Papers ISIF99
One case in point is the article by Orlando Auciello, James F. Scott, and	Update o
One case in point is the article by Orlando Auciello, James F. Scott, and Ramamoorthy Ramesh called "The Physics of Ferroelectric Memories"	Versaille
published in the July 1998 issue of Physics Today. To find out more about	Publicati
it, turn to page 16.	MRS
	On fer
On pages 15 and 16 you will find information on the latest publications of	Upcomin
the Material Research Society (MRS) , featuring low-dielectric constant	15th R
materials and topics such as stresses and mechanical properties of thin films.	Physic
In addition, you might be interested in a free copy of the 1999 MRS Publica-	Piezote
	MRS 1
tions Catalog Supplement (see order information on page 16).	112400 1
	Calendar
tions Catalog Supplement (see order information on page 16).	
tions Catalog Supplement (see order information on page16). From the National Physical Laboratory in Teddington, Middlesex, UK,	Calendar
tions Catalog Supplement (see order information on page 16). From the National Physical Laboratory in Teddington, Middlesex, UK, comes an invitation to measurement laboratories to cooperate in evaluating	

In the section Upcoming Meetings we feature the MRS 1999 Fall Meeting in	The Fe
Boston and two conferences that takes place in Russia: the 15th Russian	publishe
Conference on Physics and Ferroelectrics and Piezotechnique 99 , both	Postgrad
held at the same time and place from 14 - 18 September 1999 in Azov near	Academ
Rostov-on-Don.	nia, with
	Naval R
As has become the custom in the Ferroelectricity Newsletter, the major part	Prof.
of each issue is taken up with listing the titles and authors of presentations at	Edito
a variety of conferences. This issue is no exception. You will find the oral	e-ma
and poster papers given at the 11th International Symposium on Inte-	
grated Ferroelectrics , held from 7 - 10 March 1999 in Colorado Springs,	Dr. H
Colorado, USA. In the next issue we plan to bring you the list of presenta-	Mana
tions delivered at the Sixth Japanese - CIS/Baltic Symposium on Ferro-	500 G
•	Mon
electricity that took place in Noda, Japan, from 22 - 25 March 1998. These	phon
proceedings were published in Volume 218, Numbers 1-4 (1998) of Ferro-	fax: +
electrics .	e-ma
Rudolf Panholzer Editor-in-Chief	© 1999 N

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ISIF'99 PAPERS

The following is a list of the titles and authors of the presentations given at the 11th International Symposium on Integrated Ferroelectrics (ISIF'99) held from 7-10 March 1999 in Colorado Springs, Colorado, USA.

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Development Challenges of Gigabit Scale 1T-1C DRAMs B. Melnick	Retention Performance of SBTN FRAM Memory	S. Mitra
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High-Density FeRAMs

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Technology Perspective for 1T/1C FRAMs

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Studies of Ferroelectric Thin Film and Film-Based Device Processes Via *in situ* Analytical Techniques O. Auciello

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PIEZOELECTRICITY AND PYROELECTRICITY DATABASE (PPDB)

The database used in Professor Sidney B. Lang's "

Guide to the Literature of Piezoelectricity and which appears semiannually in Ferroelectrics is now accessible on the Gordon and Breach Internet W

The current version of the Piezoelectricity and Pyroelectricity Database (PPDB) contains references to most of the publications on piezoelectricity and pyroelectricity during the period 1990-1996. The database will be updated wit an additional 500-1000 new references about twice a year. In order to make the database as comprehensive as possible, references are included even if piezoelectricity and/or pyroelectricity formed a very minor part of the contents of the publication. The current database contains 10722 references.

References are given for articles in journals, chapters in proceedings or books, books, patents, theses and reports. F bibliographic information is given so that the reader can locate the publication. Additional information such as conference presentation data, language (if other than English) and patent assignees is given where available.

The URL for accessing PPDB is

http://www.gbhap-us.com/c3/lit_guide/

Information in the PPDB can be accessed in two ways: (1) Direct search of the database on the Internet or (2) Dow loading of the entire database and a public-domain search engine to the user's computer. Full instructions are supplied.

Any problems with the PPDB or suggestions should be sent to:

Prof. Sidney B. Lang

Department of Chemical Engineering, Ben-Gurion University of the Negev, 84105 Beer Sheva, Israel fax: +972-7-647-2916; email: lang@bgumail.bgu.ac.il

Volumes 217, 218, and 219, Numbers 1 - 4 (1998) of *Ferroelectrics* contain the proceedings of

The Sixth Japanese - CIS/Baltic Symposium on Ferroelectricity

held in Noda, Japan 22 - 25 March 1998

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VERSAILLES PROJECT

VERSAILLES PROJECT ON ADVANCED MATERIALS AND STANDARDS

Mark Gee and Markys G. Cain of the National Physical Laboratory in Teddington, UK, are initiating a project to evaluate measurement methods for determining the performance related properties of electroceramics. They are planning to enlist the cooperation of measurement laboratories interested in this project.

Electroceramics, such as piezoelectric and electrostrictive materials, have the capability of converting electrical energy into mechanical energy (or vice versa). The technological importance of these materials is increasing, with widespread applications in actuator and sensor applications.

Although there has been some standardization activity

projects cannot be fully predicted in advance of the survey. However, it is expected that w carried out at least on the development of rec procedures for the following four projects:

> 1. Measurement of piezoelectric coeffic als of differing geometries and configur including the assessment of direct and c coefficients

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through bodies such as the IEEE, and more recently through CENELEC in the development of new standards, many of the most important properties that are required for these materials when used as sensors and actuators remain without internationally recognized test methods.

Measurements where work is required include:

- * direct and converse piezoelectric coefficient measurement
- * high stress dielectric property measurement
- * the measurement of strain at high stresses, and
- * the measurement of degradation of materials performance under repeated electrical and mechanical loading.

Industries that would benefit from these activities are the manufacturers of materials, sensors, actuators, and any industries that incorporate devices based on these materials.

Although further practical measurement-based projects would be expected to follow, the subject of these

- 2. Measurement of piezoelectric strain cal/mechanical stress
- 3. Measurement of piezoelectric and dities at high stress
- 4. Measurement of electrical and mech piezoelectric ceramics materials.

Appropriate links would be developed with of the CENELEC committee (Alan Thomas) route forward to the development of standard prestandardization work performed in the Te Area is straightforward.

It is expected that the development of standa would proceed from Autumn 1999 with an e lifetime of 2-3 years.

Please direct any inquiries to:
Mark Gee & Markys G. Cain
National Physical Laboratory
Queens Road, Teddington, Middlesex, TW1
United Kingdom
phone: +44 181 943 6374/6599; fax: +44 18

email: markys.cain@npl.co.uk

Volume 220, Numbers 3-4 (1999) of Ferroelectrics is a special issue on

Ferroelectric and Related Models in Biological Systems

A collection of papers from the

Second Workshop on Nonlinear Models of Biomembrane Molecular Structures
held in Pushchino, Russia, 26 June - 1 July 1995

&

The Workshop on Condensed-state Models of Voltage-dependent Ion Channels
Kansas City, Missouri, USA, 25 February 1998

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MRS PUBLICATIONS

NEW RELEASES FROM THE MATERIALS RESEARCH SOCIETY

MRS Expands Series on Thin Films-Stresses and Mechanical Properties

The newest volume is a continuing series from the Materials Research Society, *Thin Films-Stresses and Mechanical Properties VII*, documents symposium reports from the 1997 MRS Fall Meeting in Boston, Massachusetts, and contains 95 papers, 646 pages.

Mechanical behavior in thin films continues to be a growing field of interest in the materials research community. This behavior can critically influence the design, performance, and reliability of thin-film structures used in every area of thin-film technology. Examples of affected areas include semiconductor and magnetic recording technology, as well as protective and hard-coating technology. As a result, it has become important to study and attempt to understand fundamental issues involved in film-substrate adhesion, the development of intrinsic stresses, and the mechanisms of plastic deformation, strain relaxation, and fracture in thin films.

This volume, the seventh in a popular series from the MRS, brings together an international group of researchers and students from industry, academia, and national laboratories to address the issues at hand. A great deal of work is directed toward improving existing, as well as developing new, mechanical property characterization techniques, such as more sensitive ultrasonic methods for elastic behavior determination and low-load indentation methods to investigate yield, creep, and fracture behavior. Experimental, theoretical, and modeling work is presented. Topics include: novel testing methods; low-load indentation; metallization and reliability; structural and mechanical stability; stresses and mechanical behavior; surface and tribological properties; adhesion; deformation mechanisms; stresses in thin films-generation mechanisms and measurement techniques; modeling and simulation; multilayered and superlattice thin films, and structure/ property/processing relationships.

Edited by Robert C. Cammarata (Naval Research Laboratory), Michael A. Nastasi (Los Alamos National Laboratory), Esteban P. Busso (Imperial College, University of

Symposium Proceedings Series. I hardcover or microfiche for \$62.0 \$71.00 (US list), and \$82.00 (No

MRS Introduces New Additi Low-Dielectric Constant Ma

The latest edition in the continuin Materials Research Society,

Materials IV , documents symp 1998 MRS Spring Meeting in San nia, and contains 49 papers, 386 p

While this volume continues the s science related to the developmen (low-k) constant materials, it part four major areas: polymeric and in dielectrics; metrology and charact integration and low-k interconnec low-k interconnects. These are im development of low-k dielectrics nects, where materials and proces tant role in controlling the structu reliability of the interconnect. The ened by invited and contributed p universities and industry, illustrati plinary nature of the field.

Edited by Chien Chiang (Intel Co Ho (University of Texas-Austin), (Rensselaer-Polytechnic Institute) Wetzel (Motorola Inc.), **Lo Materials IV** (ISBN: 1-55899in the MRS Symposium Proceedi available in hardcover or microfic members), \$72.00 (US list), and \$

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PUBLICATIONS

1999 MRS Publications Catalog Supplement Now Available

The 1999 Materials Research Society (MRS) Publications Catalog Supplement , containing 72 new booksall exploring interdisciplinary research on advanced materials-is now available. The volumes span many subject areas, including biomedical materials, catalysts, ceramics and composites, computational methods, electronic materials and processing, education, glasses and insulators, materials characterization, metals and alloys, novel processing/applications, nuclear waste management, polymers, sensors, and more.

Also featured in this Supplement is the new *ings of the 12th International Zeolite Conference*With four volumes and more than 3360 pages, this proceedings is one of the largest collections on zeolite science ever assembled.

To receive a free copy of the 24-page catalog, contact the Material Research Society, Customer Services Department. (For address, phone, and fax, see previous page.)

Ferroelectric Memories Featured in

Orlando Auciello (Argonne National L Argonne, Illinois, USA), James F. S New South Wales, Sydney, Australia), and Ramesh (University of Maryland, Colleg land, USA) published an article called Ferroelectric Memories" in the July Physics Today

After discussing basic ferroelectric physics, explain how NVFRAMs work and give an o early developments in the field of ferroelectr Capacitor degradation and extending the pol retention time were obstacles which could on come by using thin-film technology. But that all the problems. Today there are still basic p related issues we do not completely understa authors deal with these challenges, describe state of thin-film technology and industrial fa conclude with an evaluation of the role ferro memories will play in the future. The article figures and features two boxes: "DRAMs ba als with high permittivity" and "Other applic ferroelectric materials."

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including all back issues is available on Internet

http://www.sp.nps.navy.mil/projects/ferro/ferro.html

in Ad be Acrobat PDF file format

The PDF file format maintains the graphics and organization of the printed newsletter. Adobe Acrobat Reader is a helper application distributed free for Web browsers. Acrobat is available for Macintosh, Windows, DOS, SGI, and Sun SPARC operating systems.

If you want a hard copy of the newsletter, you must let us know by

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or rpanholzer@nps.navy.mil

mail: Hannah Liebmann, 500 Glenwood Circle, Suite 238, Monterey, CA 93940-4724 USA

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UPCOMING MEETINGS

The 15th Russian Conference on Physics of Ferroelectrics 14 - 18 September 1999 Azov, near Rostov-on-Don, Russia

Sponsored by the Ministry of General and Professional Education of Russia, the Scientific Committee of Physics of Ferroelectrics of the Russian Academy of Science, Rostov State University, Rostov State Pedagogical University, t Scientific and Research Institute of Physics at Rostov State University, and the Moscow Institute of Radio Engineer ing, Electronics and Automatics - Technical University, the 15th Russian Conference on Physics of Ferroelectrics, with the participation of foreign scientists, will be held in Azov from 14 - 18 September 1999.

Topics

- * Physical properties of ferroelectrics
- * Phase transitions and critical phenomena
- * Structure and dynamics of crystal lattice
- * Relaxor ferroelectrics
- * Surface phenomena, nanocrystals, incommensurate phases, etc.
- * Domain structure and processes of switching

* Physical properties and processes in ceramics and compound materials

Forms of Presentati n

- * Plenary presentation (40 minutes)
- * Original presentation (15 minutes)
- * Poster presentation
- * Official languages are Russian and English

Organizing Committee:

- K. S. Alexandrov (Krasnoyarsk) chairman
- A. A. Grekov (Rostov-on-Don) vice-chairman
- V. P. Sakhnenko (Rostov-on-Don) vice-chairman
- I. N. Chugueva (Moscow) scientific secretary
- E. V. Bursian (St. Petersburg)
- T. R. Volk (Moscow)
- S. A. Gridnev (Voronez)
- V. V. Lemanov (St. Petersburg)
- V. K. Malinovsky (Novosibyrsk)
- A. S. Sygov (Moscow)
- B. A. Strukov (Moscow)
- A. V. Shilnikov (Volgograd)
- L. A. Shuvalov (Moscow)
- V. Y. Shur (Ekaterinburg)

Contact

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UPCOMING MEETINGS

Piezotechnique 99 14 - 18 September 1999 Az v, near Rostov-on-D n, Russia This international conference covering scientific and practical aspects of fundamental problems of piezoelectricity and its applications is sponsored by the Ministry of General and Professional Education of Russia, the Russian Space Agency, Rostov State University, the Scientific & Technological Bureau Piezopribor at Rostov State University, as well as the Scientific and Research Institute of Physics at Rostov State University.

Topics

- * Theoretical modeling and design of piezoelectric transducers and devices
- * Application of materials for piezotechnique devices
- * Theoretical and experimental investigations on physics of piezoelectric transducers, on polarization processes, and technological aspects of piezomaterials processing
- * Piezoelectric materials science
- * Special instruments for investigation and testing of piezomaterials, sensors and piezoelectric transducers
- * Detecting and transforming devices, nondestructive testing devices, filters, drives, piezomotors, piezotransformers, ultrasound systems, medical equipment and household appliances
- * New directions of piezotechnique (smart materials, hybrid structures, nontraditional piezoelectric systems, nanotechnology, etc.)
- * Exhibition of piezoelectric products (materials, technologies, active elements, devices), presentation and sale of scientific and technical materials (monographs, proceedings, advertisement prospects etc.)

Exhibitions and Company Participation

Domestic and foreign piezoelectric companies are welcome to participate. Companies could present a talk as well as exhibit samples of their products.

Proceedings

The presentations will be published before the beginning of the conference as

Conference Proceed

Organizing Committee

A. E. Panich (Rostov-on-Don) - chairman

V. P. Sakhnenko (Rostov-on-Don) - chairman

A. V. Gorish (Moscow) - vice-chairman

V. K. Dolya (Rostov-on-Don) - vice-chairman

V.Y. Topolov (Rostov-on-Don) - scientific secretary

The 15th Russian Conference on Physics of Ferroelectrics

is held simultaneously with

Piezo

pants of Piezotechnique 99 can attend the 15th Russian Conference on Physics and Ferroelectrics without additional fee.

Contact

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Ferroelectricity Newsletter

UPCOMING MEETINGS

Materials Research Society 1999 Fall Meeting 29 November - 3 December 1999 Boston, Massachusetts, USA

The Fall 1999 Materials Research Society Meeting will highlight recent and significant advances in the understand and synthesis of materials. More than 40 technical symposia will cover a wide range of topics in materials science, including self-assembled and nanostructured materials, surfaces and interfaces, thin-film materials and processes, s materials including biological applications, semiconductor devices, ceramics, structural materials, and materials modeling.

New symposia will be offered in many exciting areas, such as biomineralization, the materials science of food, complex fluids, superplasticity, molecular electronics, and smart materials. Popular ongoing series of symposia wil continue in nitride semiconductors, ferroelectric thin films, nanophase and nanocomposite materials, high-temperat superconductors, the materials science of MEMS devices, interfacial engineering and epitaxy, and nuclear waste management. Symposia on computer modeling and calculations in materials science will provide a forum for interation between theorists and experimentalists. Strong interaction among the symposia will highlight the interdisciplinary nature of materials science.

Tutorial sessions in selected areas will provide introductions to new fields. There will be an exhibition of products and services of interest to the materials community, and the popular Symposium X series will feature topics on the forefront of materials science.

Sample of Symposia

- * T: Structure and electronic properties of ultrathin dielectric films on silicon and related structures
- * V: Thin Films-Stresses and mechanical properties VIII
- * Y: Ferroelectric thin films VIII
- * Z: Thin films for optical waveguide devices

Abstracts

For all abstracts submitted by email, fax, or mail, the deadline is 7 June 1999 Because th submit an abstract is via the MRS Website-the choice of more than 90 percent of submitting authors-the deadlin for abstracts submitted via the Website will be extended until 21 June 1999

For specific technical information, c ntact any of the 1999 Fall Meeting Chairs

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Website

www.mrs.org

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CALENDAR OF EVENTS 1999

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Jun 7-10	*	Transducers '99: The 10th International Conference on Solid-State Sensors and Actuators, Sendai, Japan (see Ferroelectricity Newsletter, Vol. 6, No. 3, p.17)
Jun 20-25	*	Gordon Research Conference on Thin Films and Crystal Growth Mechanisms, Plymouth State College, Plymouth, New Hampshire, USA Gordon Research Conferences, University of Rhode Island, PO Box 984, West Kingston, RI 02894-0984; phone: +401-783-4011; email: grc@grcmail.grc.uri.edu Website: http://www.grc.uri.edu
Jun 24-26	*	3rd Korea-Japan Conference on Ferroelectrics, Kyungju, Korea (see Ferroelectricity Vol. 6, Nr. 4, p. 35)
Jul 12-16	*	9th European Meeting on Ferroelectricity (EMF-9), Prague, Czech Republic (see Newsletter . Vol. 6, No. 3, p. 18)
Jul 31- Aug 1	*	Short Course on Crystal Growth, Tucson, Arizona, USA (see Ferroelectricity Newslett No. 3, p. 19)
Aug 1-6	*	11th American Conference on Crystal Growth and Epitaxy, Tucson, Arizona, USA (see <i>Newsletter</i> , Vol. 6, No. 3, p. 19)
Aug 4-13	*	18th International Union of Crystallography and General Assembly, Glasgow, Scotland

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Aug 29- Sep 3	*	7th International Conference on Ferroelectric Liquid Crystals (FLC 99), Darmstadt, Germany (see Ferroelectricity Newsletter, Vol. 7, No. 1, p. 23)
Sep 14-18	*	15th Russian Conference on Physics of Ferroelectrics, Rostov-on-Don, Russia (see p. 17)
Sep 14-18	*	Piezotechnique 99, Rostov-on-Don, Russia (see p. 18)
Sep 30- Oct 2	*	European Conference on Macromolecular Physics (EPS'99), Potsdam, Germany (see <i>Newsletter</i> , Vol. 7, No. 1, p. 23)
Nov. 29- Dec. 3	*	MRS 1999 Fall Meeting, Boston, Massachusetts, USA (see p. 19)